

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	Confirmation No.: 5877
Kenichi MORIMOTO	Art Unit: 1763
S. N. 10/737,393	Examiner: Allan W. Olsen
Filed: December 16, 2003	

For: MASK BLANK FOR CHARGED PARTICLE BEAM EXPOSURE, METHOD OF
FORMING MASK BLANK AND MASK FOR CHARGED PARTICLE BEAM EXPOSURE

SUPPLEMENTAL RESPONSE TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Further in response to the response to office action
submitted December 17, 2007, in reply to the office action dated
July 16, 2007, please make the following amendments:

Claim amendments begin on page 2 of this document.

Remarks begin on page 4 of this document.